

HD Supercell PDE measurements in LAr @ MiB: improving light guide sealing

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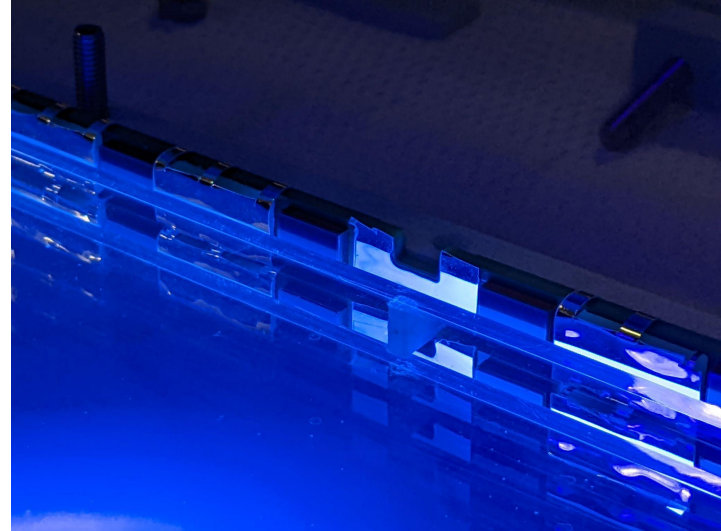
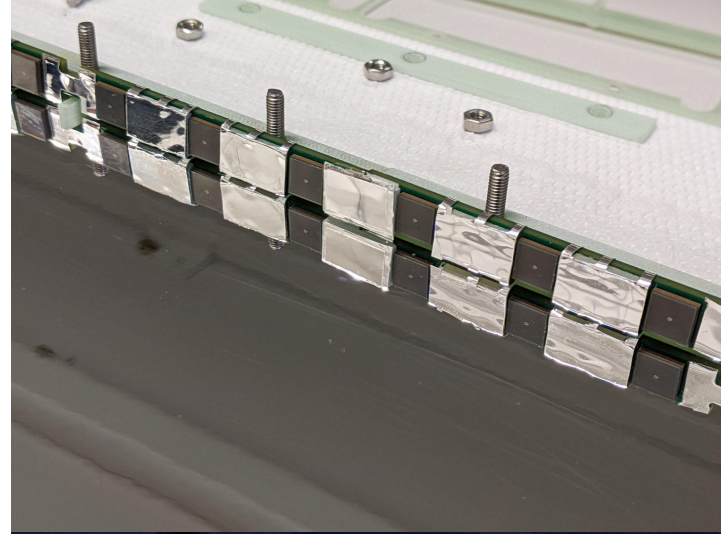
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HD-XA Supercell PDE measurements & simulations

- **measurements** from january and march with **increased light sealing**:
 - **same SC** with **Vikuiti on G10 blocks between SiPMs**
 - **Vikuiti** on one of the **long light guide edges**
 - **new light guide** (protoDUNE run2 batch)
 - **new light guide (ZAOT vs OPTO)**
 - **new light guide (OPTO only)**
- optical simulation to study **PDE dependence** on:
 - light guide edge - SiPM (Vikuiti) **distance**
 - different **light guide configurations**
 - WLS dye concentration (**attenuation length**)

HD-XA Supercell with Vikuiti blocks

- placing Vikuiti closer to the light guide provides better light sealing
 - could be the reason the previous 2-cell XA version had better PDE
- this week we will measure a SC with Vikuiti on G10 blocks between the SiPMs to verify
- we also planned a measure with half the SiPMs blinded with Vikuiti to check if a better light sealing could allow a lower number of SiPMs to collect the light
 - dependent on the PMMA absorption (known only a lower limit)

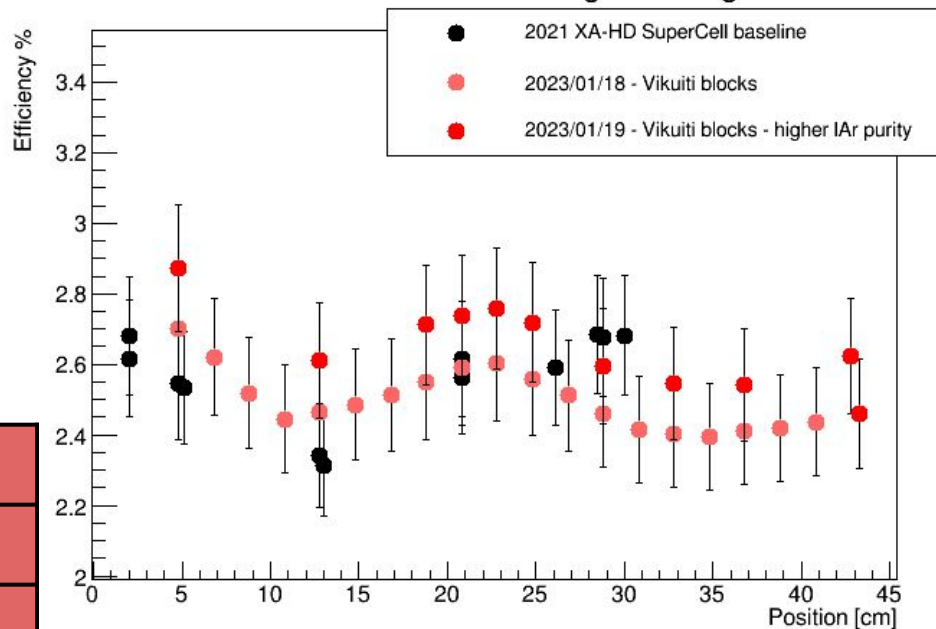


18-19/01/23 - Increased light sealing

- for this measurements the **same SC from 2021** has been used (**frame, HPK SiPMs, G2P Ig and OPTO filters**)
- **added Vikuiti covered G10 spacer blocks between each SiPM**
- **...no significant increase over baseline**
- increase in PDE after one day -> higher LAr purity?

measure	baseline	18/01	19/01
avg PDE	2.51%	2.49%	2.64%
% wrt bl	-	-1%	+5%

HPK G2P - increased light sealing

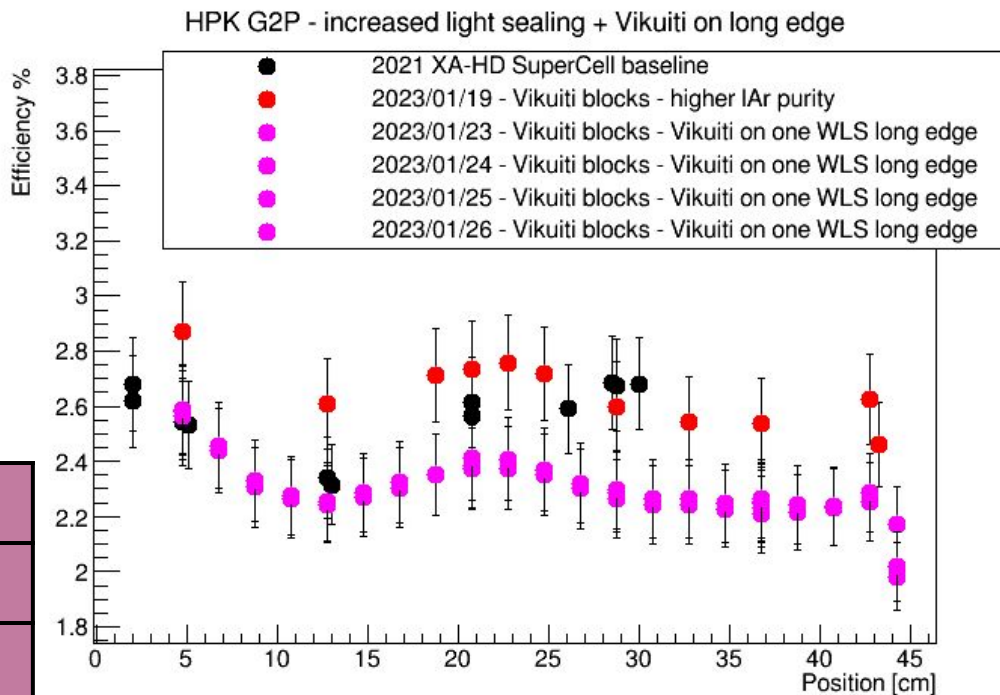


all efficiency values in this talk are WITHOUT x-talk and LAr purity corrections

23-26/01/23 - Vikuiti on light guide long edge

- Vikuiti placed on one of the light guide long edges
 - **1/3 of the SiPM surface blinded (66% active)**
- **lower PDE, as expected, but still 87% of previous meas.**
 - light can easily be reflected to the SiPMs on the other side (~10cm)

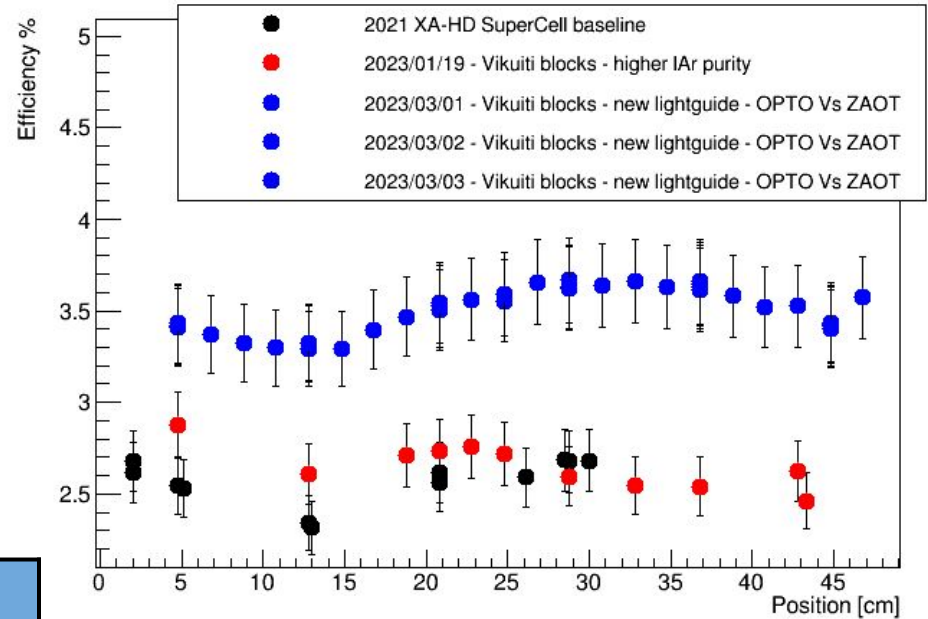
measure	baseline	19/01	23-26/01
avg PDE	2.51%	2.64%	2.29%
% wrt bl	-	+5%	-8%
% wrt 19/01	-	-	-13%



01-03/03/23 - new light guide, OPTO vs ZAOT

- the **light guide** used until last measurement has been exchanged with one from the **protoDUNE run2 batch**
 - same specs but:
 - slightly wider (92.2mm -> 93mm)
 - more uniform in width
- observed 40% increase in PDE wrt baseline as simulations suggest**
 - width?
 - surface finish?

HPK G2P OPTO vs ZAOT - increased light sealing + new light guide



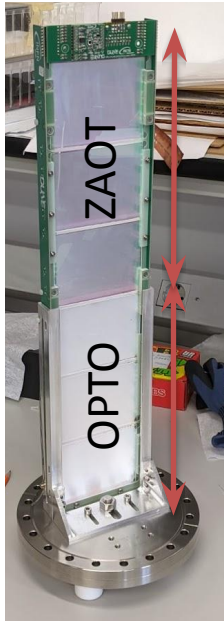
← average of the entire SC (OPTO and ZAOT)

measure	baseline	19/01	01-03/03
avg PDE	2.51%	2.64%	3.49%
% wrt bl	-	+5%	+39%

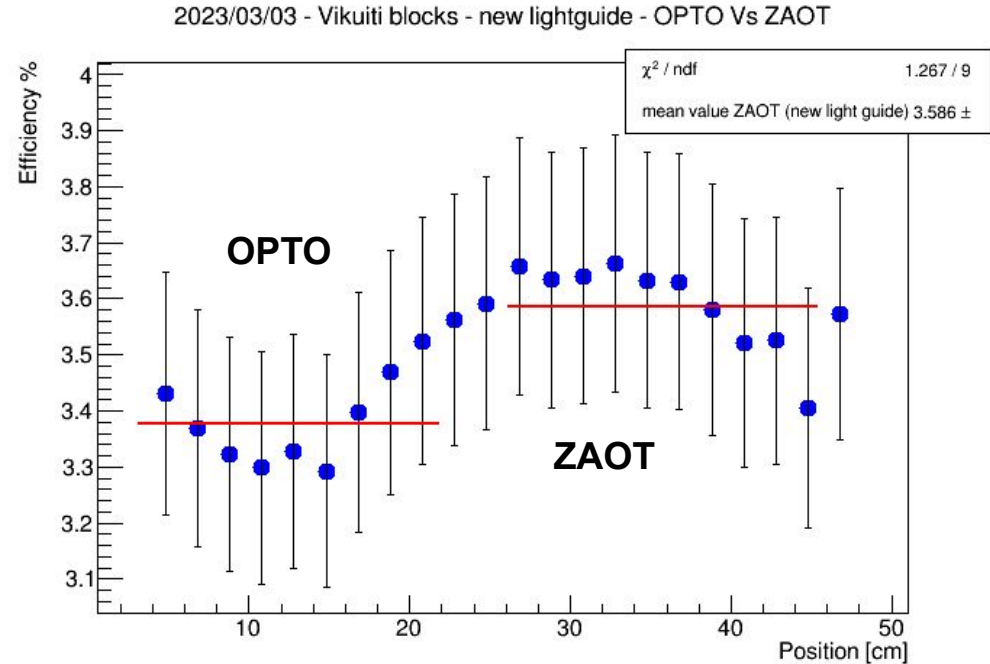
01-03/03/23 - new light guide, OPTO vs ZAOT

- **ZAOT filters perform better**

- hard to quantify because the SC is not divided in two
- we have planned a measurement with ZAOT only



dichroic	PDE [%]
ZAOT	3.58
OPTO	3.38



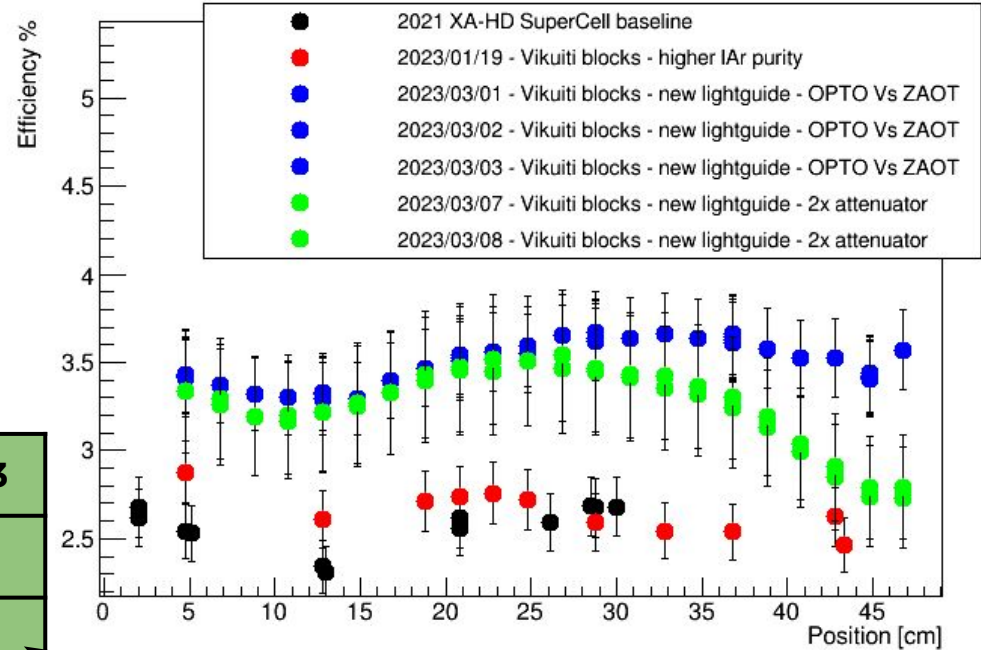
**6% higher PDE
(lower limit)**

07-08/03/23 - new light guide, OPTO only

- **observed same increase in PDE as the previous measurement**
- **OPTO filters perform worse, as expected**
 - decrease in PDE in the top part due to spreading damage on pTP

measure	baseline	19/01	01-03/03
avg PDE	2.51%	2.64%	3.35%
% wrt bl	-	+5%	+33%

HPK G2P OPTO only - increased light sealing + new light guide

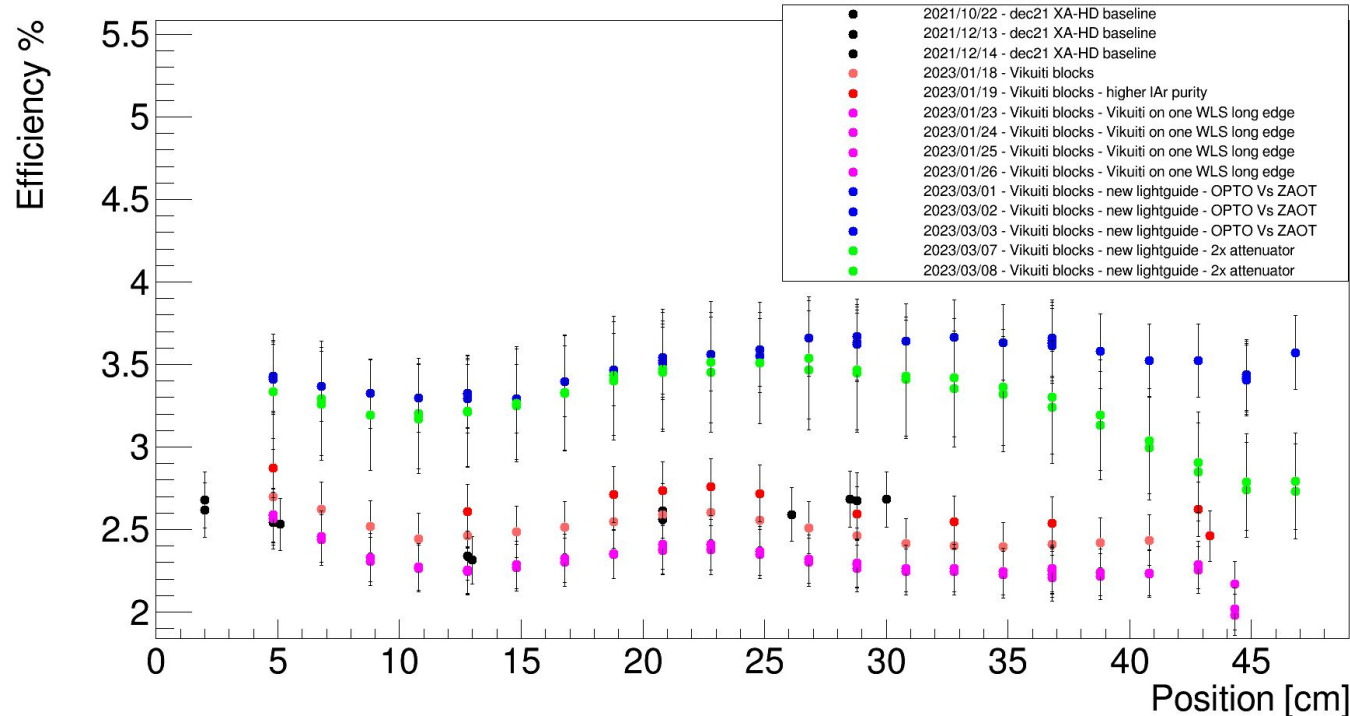


average of the SC up to 37cm due to pTP damage on the last 2 filters

Measurement summary - January and March 2023

- **higher PDE likely due to better light sealing**

HPK G2P flat WLS



- **baseline 2021**

+ improved light sealing

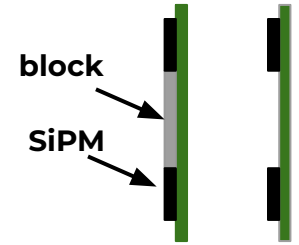
- **same config**
- **Vikuiti on long edge**

+ new light guide:

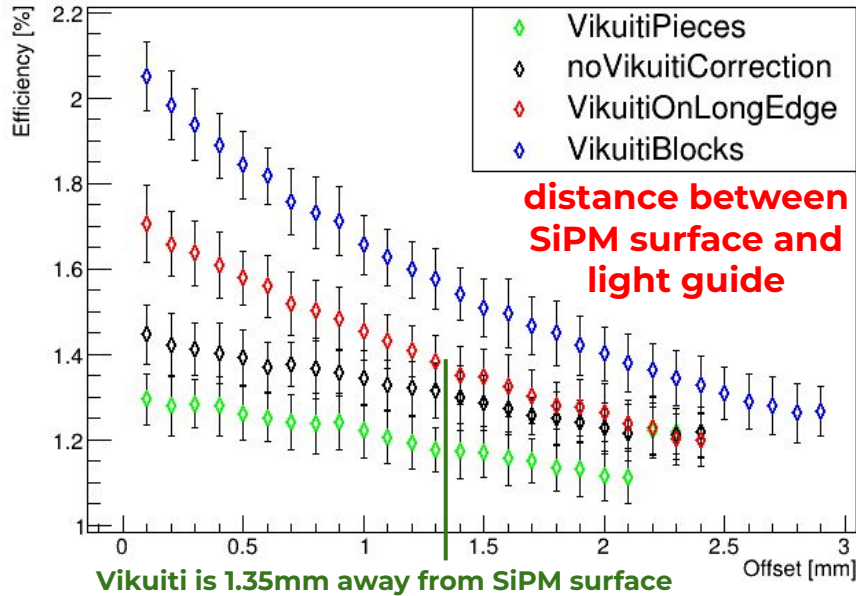
- **OPTO vs ZAOT**
- **OPTO only**

Simulation - distance between SiPMs and light guide

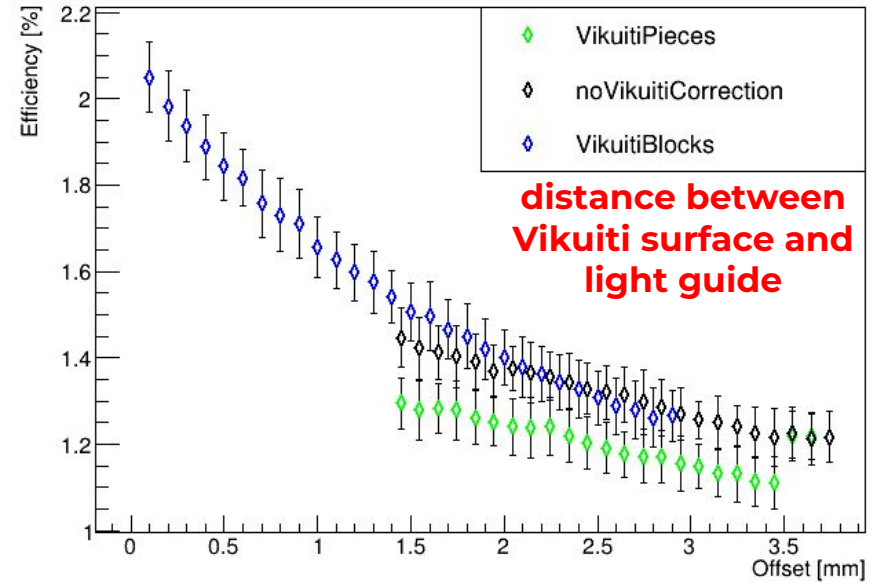
- **PDE is strongly dependent on the SiPM-Ig distance**
 - **distance of the Vikuiti reflector** seems to be the main factor



SiPM Offset Scan

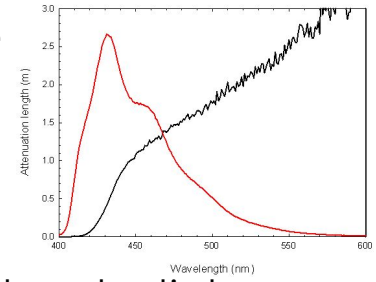


SiPM Offset Scan

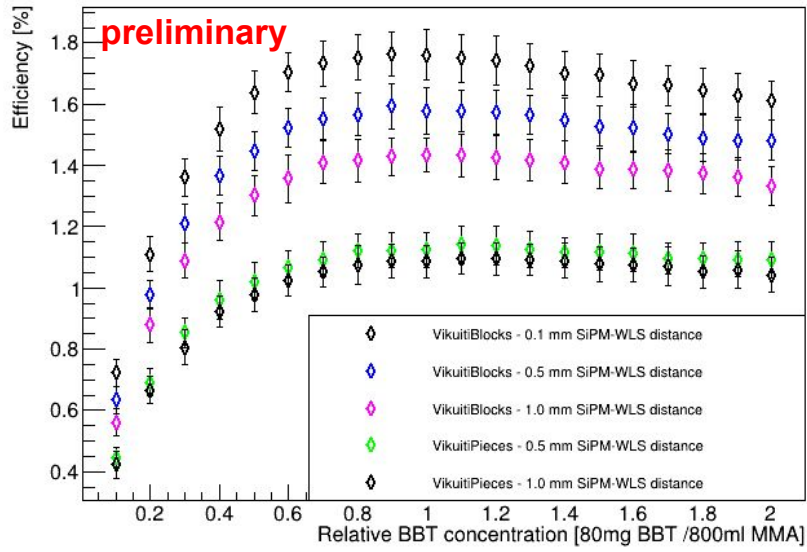


Simulation - WLS dye concentration (Attenuation length)

- G2P provided us the **attenuation curve** of the **PMMA with BBT dye**
 - **attenuation length depends on the BBT concentration**
 - through simulation, different attenuation curves can be tested to **obtain the optimal concentration for a given geometry**



BBT concentration scan

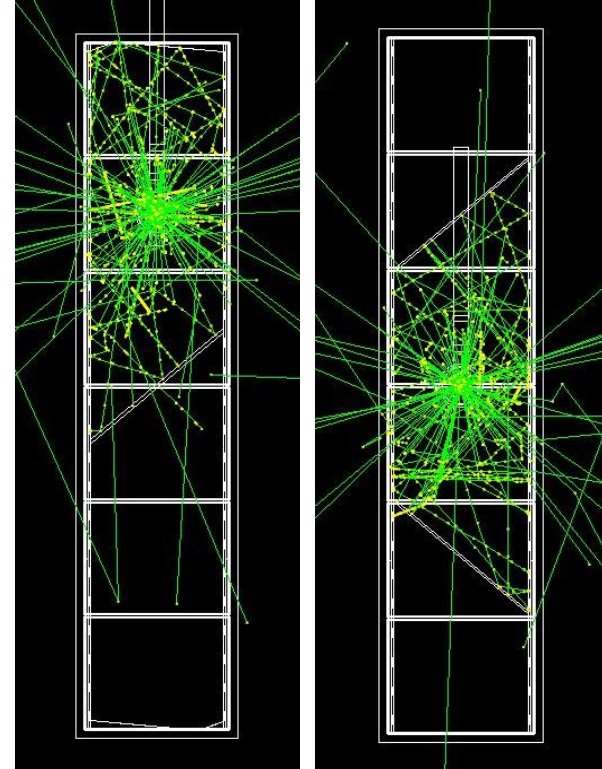
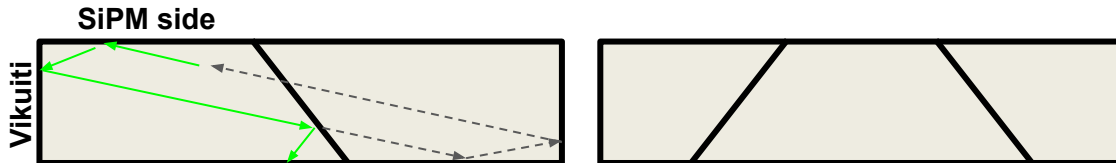


- the higher the curve the higher the light sealing in the plot shown here
- a higher light sealing increases the maximum light path
 - light is better trapped
- a lower dye concentration allows light to travel more in the light guide

=> an optimum is found at lower dye concentration when the possible light path is higher

Simulation - light guide configurations

- a different geometry of the light guide could improve the PDE
- cutting the lg with an angle (about 40°) can help more light escape
 - also decreases the distance light has to travel to reach a SiPM
 - mechanical constraints?
- simulated configurations:
 - **2 piece WLS, one 40° cut in the middle**
 - **3 piece WLS, two cuts ($\pm 40^\circ$)** (problem with lg supports)

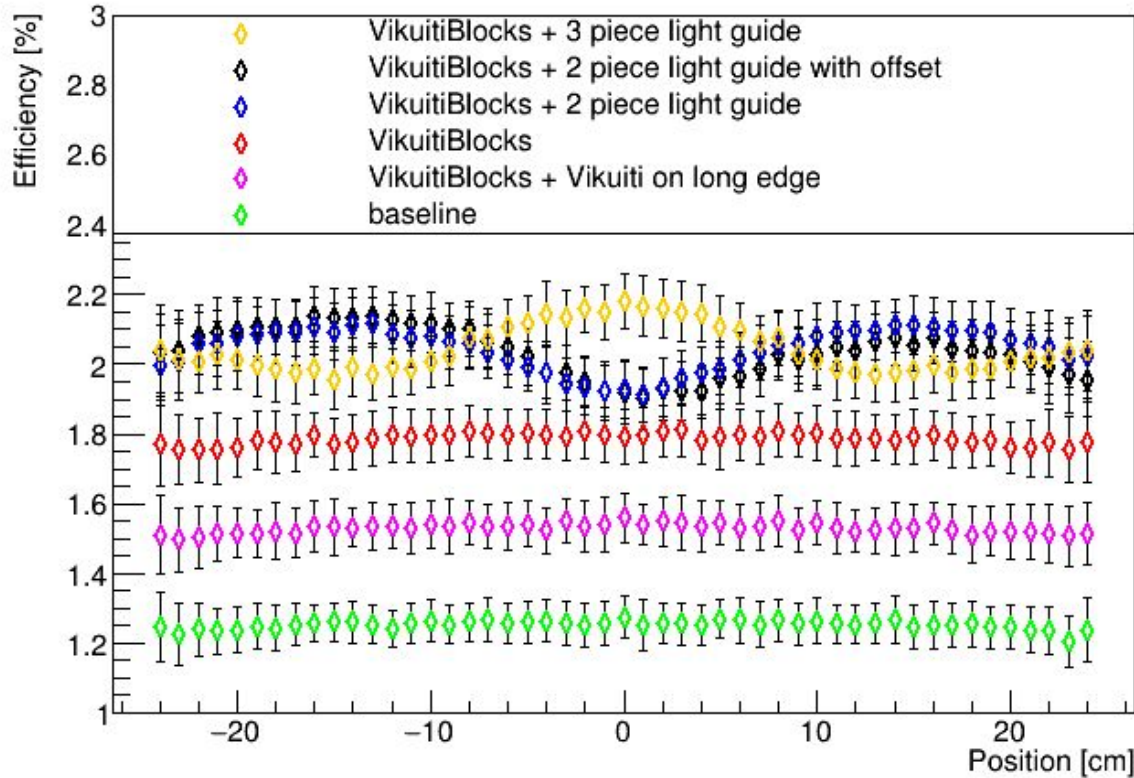


Simulation - light guide configurations

- cutting the SC also causes **disuniformity in the light collection** along the Z direction
 - less increase in PDE near the cut
- **simulated different SC configs Z scans with the SiPM distance fixed at 0.5mm**
 - then average all the positions
- **this plot can vary a lot depending on the fixed variables**
 - SiPM distance
 - light guide attenuation length
 - ...

Simulation - light guide configurations

Supercell Scan - 0.5mm SiPM-WLS dist

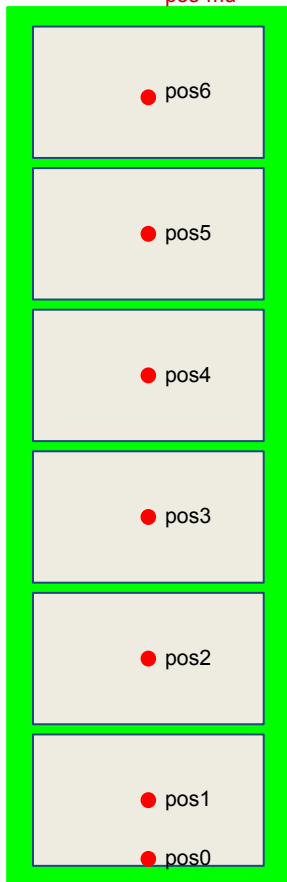


config	average PDE*	% wrt baseline
baseline	1.25	-
VB + VonLE	1.53	+22%
Vikuiti Blocks	1.79	+43%
VB + 2 piece WLS	2.04	+63%
VB + 2 piece offs	2.04	+63%
VB + 3 piece WLS	2.04	+63%

Backup

Method & Data taking

pos-mu



z-scanning of the SC with the ^{241}Am α (5.480 MeV) source at the following positions:

1. **pos0**: (the lowest possible): ~ 2 cm above the flange.
2. **pos1, 2, 3, 4, 5, 6**: the center of each dichroic filter.
Acquired: $10^4 \times 4$ wfms; 20 μs length; ~ 5 μs pretrigger.
3. Source at the topmost position (~ 49 cm from the flange) and \sim out of LAr:
 - one **μ run** ($10^4 \times 4$ events; 20 μs , 5 μs pretrigger)
 - one **s.p.h.e. run** ($10^4 \times 8$ events; 20 μs length; 1.6 μs pretrigger)

Source-to-dichroic filter distance: (55 +/- 1) mm.

Noise Run: $V_{\text{bias}} = V_{\text{bd}} - 1\text{V}$ for FFT and filter shape&cutoff definition

[pTP - glass substrate - dichroic] modeling

- in geant4 the modeling of the pTP deposit and dichroic filter is difficult:
 - need to know pTP refractive index and opacity
 - determine the amount of light able to escape the pTP volume
 - only one dichroic surface can be defined...
 - at least 2 needed since the dichroic behaviour should depend on the material the light is travelling through (IAr or glass)
- i.e. a large improvement in geant4 is given by an increased glass substrate refractive index
 - this changes the a.o.i of the light coming from the pTP to the dichroic
 - a change in the dichroic behaviour wrt material RI could negate this improvement

ZAOT nov22 substrate RI	PDE	% wrt 1.49
1.49	2.30%	-
1.55	2.74%	+19%
1.7	4.02%	+75%
1.8	4.35%	+89%

=> for now the amount of light entering the SC is not accurately modeled...